



#910
1-22-02
Harrison

Patent

In re application of:
Thomas A. Figura et al.

Serial No.: 09/470,650

Filed: December 22, 1999

For: USE OF A PLASMA SOURCE TO
FORM A LAYER DURING THE
FORMATION OF A SEMICONDUCTOR
DEVICE

§ Group Art Unit: 2813
§
§ Examiner: Lisa Kilday
§
§ Atty. Docket: 94-0280.04
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Certificate of Mailing (37 C.F.R. § 1.8)

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail, postage prepaid, in an envelope addressed to: Commissioner for Patents, Washington, D.C. 20231, on the date below:

11/8/01 Date Signature *Susan Jerome*

PETITION FOR EXTENSION OF TIME UNDER 37 C.F.R. § 1.136(a)

Commissioner for Patents
Washington, D.C. 20231

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Dear Sir:

Applicants hereby petition to extend the period for response to the Office Action mailed August 6, 2001 for one (1) month, from November 5, 2001 to December 6, 2001.

Accordingly, the requisite fee is \$ 110. The Commissioner is requested to charge this fee, and any additional fee which may be required to Micron Technology, Inc. Deposit Account 13-3092, Order No. 94-0280.04. A duplicate copy of this petition is enclosed.

Respectfully submitted,

Date: 11/7/1

Charles B. Brantley

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